



IFM 1765

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **YAMADA, Toshiro, et al.**

Group Art Unit: 1765

Serial No.: 10/520,272

Examiner: **Shamim Ahmed**

Filed: **January 14, 2005**

P.T.O. Confirmation No.: 4526

**FOR: METHOD OF DRY ETCHING, DRY ETCHING GAS AND PROCESS FOR
PRODUCING PERFLUORO-2-PENTYNE**

AMENDMENT UNDER 37 CFR §1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

March 12, 2007

Sir:

In response to the Office Action dated **December 11, 2006** with **March 11, 2007** being a
Sunday, please amend the above-identified application as follows: